

# ISO 16531:2013-06 (E)

Surface chemical analysis - Depth profiling - Methods for ion beam alignment and the associated measurement of current or current density for depth profiling in AES and XPS

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<b>Contents</b>		<b>Page</b>
Foreword .....		iv
Introduction .....		v
<b>1</b>	<b>Scope .....</b>	<b>1</b>
<b>2</b>	<b>Normative references .....</b>	<b>1</b>
<b>3</b>	<b>Terms, definitions, symbols and abbreviated terms .....</b>	<b>1</b>
<b>4</b>	<b>System requirements .....</b>	<b>2</b>
<b>4.1</b>	<b>General .....</b>	<b>2</b>
<b>4.2</b>	<b>Limitations .....</b>	<b>2</b>
<b>5</b>	<b>Ion beam alignment methods .....</b>	<b>3</b>
<b>5.1</b>	<b>General .....</b>	<b>3</b>
<b>5.2</b>	<b>Important issues to be considered prior to ion beam alignment .....</b>	<b>3</b>
<b>5.3</b>	<b>Alignment using circular-aperture Faraday cup .....</b>	<b>6</b>
<b>5.4</b>	<b>Alignment using elliptical-aperture Faraday cup .....</b>	<b>9</b>
<b>5.5</b>	<b>Alignment using images from ion-induced secondary electrons during ion beam rastering .....</b>	<b>9</b>
<b>5.6</b>	<b>Alignment in X-ray photoelectron microscope/photoelectron imaging system .....</b>	<b>11</b>
<b>5.7</b>	<b>Alignment by observing direct ion beam spot or crater image during and/or after ion sputtering .....</b>	<b>12</b>
<b>5.8</b>	<b>Alignment by observing phosphor sample .....</b>	<b>13</b>
<b>6</b>	<b>When to align and check ion beam alignment .....</b>	<b>13</b>
	<b>Annex A (informative) Comparison of AES depth profiles with good/poor ion beam alignment .....</b>	<b>14</b>
	<b>Annex B (informative) Alignment using cup with co-axial electrodes .....</b>	<b>16</b>
	<b>Bibliography .....</b>	<b>18</b>